

SHEET 1 OF 4

Form PTO 1449 (Modified)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY DOCKET NO. 231752US26YA	SERIAL NO. 10/673,467
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT Eric J STRANG	
		FILING DATE September 30, 2003	GROUP 2128

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
/A.S./	AA US 6,571,371	5/2003	Coss, et al.			
	AB US 6,763,277	7/2004	Allen, et al.			
	AC US 6,529,789	3/2003	Campbell, et al.			
	AD US 6,628,809	9/2003	Rowe, et al.			
	AC US 6,728,591	4/2004	Hussey, et al.			
	AC US 6,774,998	8/2004	Wright, et al.			
	AC US 2005/0016947	1/2005	Fatke, et al.			
	AH US 2005/0010319	1/2005	Patel, et al.			
	AI US 2003/0078738	4/2003	Wouters, et al.			
	AJ US 2004/0078319	4/2003	Madhavan, et al.			
	AK US 5,866,437	2/1999	Chen, et al.			
	AL US 2004/0044513	3/2004	Kitahara, Noriaki			
	AM US 2004/0102934	5/2004	Chang, Fang-Cheng			
/A.S./	AN US 2003/0135302	7/2003	Hung, et al.			

## FOREIGN PATENT DOCUMENTS

Not Provided.	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
				YES	NO
	AC CN 1325555A	2/13/2003	China (with Partial English Translation)	X	
/A.S./	AP WO 02/07210 A2	1/24/2002	WIPO		X
	AQ EP 0 718 593 A2	6/26/1996	EUROPE		X
	AR JP 2004-527117	9/2/2004	Japan		X
	AS WO 03/060779 A1	7/24/2003	WIPO		X
	AT JP 2005-515623	5/26/2005	JAPAN (With English Abstract)		X
V	AU WO 03/099345 A2	1/30/2003	WIPO		X
/A.S./	AV JP 2005-522018	7/21/2005	JAPAN (With English Abstract)		X

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

AW	Robert W. ATHERTON, et al., "Detailed Simulation for Semiconductor Manufacturing", Proceedings of the 1990 Winter Simulation Conference	<input type="checkbox"/> Additional References sheet(s) attached
AX	Angus J. MACDONALD, et al, "Integrated CAM and Process Simulation to Enhance On-Line Analysis and Control of IC Fabrication", IEEE Transactions on Semiconductor Mfg., Vol. 3, No. 2, May 1990	
AY	Paul P. CASTRUCCI, "Emerging Paradigms in Semiconductor Manufacturing"; 1990 Int'l Semiconductor Mfg., Science Symposium, IEEE 1990	
AZ	Yea-Huey SU, et al. "Conceptual Framework for Manufacturing Service Provisioning by Virtualfabs"; 1998 NSC Republic Of China; 1998 Semiconductor Mfg. Technology Workshop	

Examiner /Akash Saxena/ (12/15/2010) Date Considered 12/15/2010

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO 1449 (Modified)		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. <b>231752US26YA</b>	SERIAL NO. <b>10/673,467</b>
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT <b>Eric J STRANG</b>	
				FILING DATE <b>September 30, 2003</b>	GROUP <b>2128</b>
<b>U.S. PATENT DOCUMENTS</b>					
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
/A.S./	AAA US 6,615,097	9/2003	Ozaki, Hiroji		
↓	AAB US 6,905,895	6/2005	Coss, et al.		
AAC	US 6,757,645	6/2004	Chang, et al.		
↓	AAD US 6,643,616	11/2003	Granik, et al.		
/A.S./	AAE US 6,618,856	9/2003	Coburn, et al.		Duplicated
	APP US 2004/0844515	3/2004	Kinoshita, Noriaki		
/A.S./	AAG US 2005-0071037	3/31/2005	Strang		
↓	AAH US 2005-0071035	3/31/2005	Strang		
AII	US 2005-0071038	3/31/2005	Strang		
↓	AAJ US 2005-0071036	3/31/2005	Mitrovic		
AAK	US 2005-0071039	3/31/2005	Mitrovic		
/A.S./	AAL US 6,198,980 B1	3/2001	Costanza, John R.		
	AAM				
	AAN				
<b>FOREIGN PATENT DOCUMENTS</b>					
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
				YES	NO
/A.S./	AAO JP 2003-17471	1/17/2003	JAPAN (With English Abstract)		X
	APP WO 02/065511 A2	8/22/2002	WIPO		X
↓	AAQ JP 2004-524685	8/12/2004	JAPAN		X
AAR	WO 02/069063 A2	9/6/2002	WIPO		X
↓	AAS JP 2004-531878	10/14/2004	JAPAN		X
AAT	JP 2000-517473	12/26/2000	JAPAN (With English Abstract)		X
↓	AAU WO 03/058699 A1	7/17/2003	WIPO		X
AAV	JP 2005-514790	5/19/2005	JAPAN (With English Abstract)		X
<b>OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)</b>					
AAW	Chanette RASMIDATTA, et al. "New approaches for Simulation of Wafer fabrication : The Use of Control Variates and Calibration Metrics" Proceedings of 2002 Winter Simulation Conference, 2002				
AAX					
AAY					
AAZ					
Examiner	/Akash Saxena/ (12/15/2010)			Date Considered 12/15/2010	
<input type="checkbox"/> Additional References sheet(s) attached					

\* Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 231752US26YA	SERIAL NO. 10/673,467		
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Eric J STRANG			
				FILING DATE September 30, 2003	GROUP 2128		
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
/A.S./	AAAA	US 7,107,571 B2	9/2006	Chang, et al.			
	AAAB	US 5,741,070	4/21/1998	Mehrdad Mahmud Moslehi			
	AAAC	US 2004/0058255 A1	3/25/2004	Scott Jessen, et al			
	AAAD	US 5,539,652	7/23/1996	Tegethoff			
	AAAF	US 6,581,029 B1	6/17/2003	Fisher			
	AAAF	US 2003/0003607	1/2/2003	Kagoshima et al			
	AAAC	US 6,185,472	2/6/2001	Onga, et al.			
	AAAH	US 7,047,095 B2	5/16/2006	Tomoyasu			
/A.S./	AAAI	US 6,587,744 B1	7/1/2003	Stoddard, et al.			
	AAAJ						
	AAAK						
	AAAL						
	AAAM						
	AAAN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES	NO	
/A.S./	AAAO	JP 2002-367875	12/20/2002	JAPAN		X	
/A.S./	AAAF	JP 2003-502771	1/21/2003	JAPAN		X	
/A.S./	AAAQ	WO 02/077589 A2	10/3/2002	WIPO		X	
	AAAR					X	
	AAAS					X	
	AAAT					X	
	AAAU					X	
	AAAV					X	
	AAAW					X	
	AAAX					X	
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AAA	Su-shing CHEN, "AEMPES: An expert system for in-situ diagnostics and process monitoring"; Semiconductor Manufacturing Science Symposium, 1998, IEEE/SEMI International, 21-23 May 1998 Pages 119-122					
/A.S./	AAAZ	Heru SETYAWAN, et al. "Visualization and numerical simulation of fine particle transport in a low-pressure parallel plate chemical vapor deposition reactor", Chemical Engineering Science 57 (2002) pages 497-506					
Examiner	/Akash Saxena/ (12/15/2010)				Date Considered		
<input type="checkbox"/> Additional References sheet(s) attached							
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							